



566.41191X00

Applicants: Y. KURATA, et al.
Serial No.: 10/049,672
35 USC 371 Date: APRIL 30, 2002
Title: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL
POLISHING, AND METHOD OF POLISHING SUBSTRATE
MEMBER
Group AU: 1765
Examiner: Duy Vu Nguyen Deo
Confirm. No: 7706

AMENDMENT

Mail Stop: AMENDMENT – FEE

Commissioner for Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

February 13, 2006

Sir:

In response to the Office Action dated August 11, 2005, the period for response having been extended for three (3) months by the attached Petition for Extension of Time, please amend the above-identified application as listed in the following, and as set forth on the following pages:

AMENDMENTS TO THE CLAIMS; and

REMARKS are included following the amendments.